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REPLY UNDER 37 C.F.R. § 1.116 EXPEDITED PROCEDURE **EXAMINING GROUP 1765**

> PATENT 5298-06900/PM01027

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Schwarz

Serial No. 10/074,888

Filed: February 13, 2002

For:

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WITHIN AN ETCHED

SEMICONDUCTOR TOPOGRAPHY

Group Art Unit: 1765 Examiner: Deo, D.

Any. Dkt. No. 5298-06900

I bereby certify that this corre Thereby certary treat can correspondence to octog statements via facelimits or deposited with the U.S. Postal dervice with sufficient postage as First Class Mall in an envelope addressed for Commissioner for Patents, P.O. Box 1460, Air 22313, on the date indicated below:

ografie<u>r 16, 2004</u> Date

AMENDMENT; RESPONSE TO FINAL OFFICE ACTION DATED JULY 23, 2004

Mall Stop AF Commissioner for Palents P.O. Box 1450 Alexandria, VA 22313

Dear Sir/ Madam:

This paper is submitted in response to the final Office Action dated July 23, 2004 to further highlight reasons why the application is in condition for allowance.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks begin on page 7 of this paper.

SN 10/074,888 Response to Final Office Action Mailed 7/23/2004

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